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JC974 U.S. PRO  
09/776009  
02/02/01



## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants : Michael A. Vyvoda et al.

For : WAFER SURFACE THAT FACILITATES  
PARTICLE REMOVAL

Serial No. : To Be Assigned

Hon. Assistant Commissioner  
for Patents  
Washington, D.C. 20231

125105  
D. Wilson  
1-13-02

INFORMATION DISCLOSURE STATEMENT

Sir:

In accordance with 37 C.F.R. §§ 1.56, 1.97, and 1.98, applicants wish to call the attention of the Examiner to the following documents:

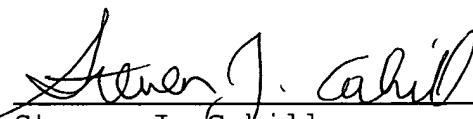
U.S. Patents

|                |           |         |
|----------------|-----------|---------|
| Johnson et al. | 6,034,882 | 03/2000 |
| Zhang          | 5,835,396 | 11/1998 |

These documents are listed on the accompanying Form PTO-1449 (submitted in duplicate) and copies are enclosed herewith.

Consideration of the foregoing in relation to this patent application is respectfully requested.

Respectfully submitted,



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